



Corres. and Mail
BOX AF

Reply under 37 CFR 1.116
Expedited Procedure
Examining Group 1756

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Ko et al.

Application No: 09/894,230

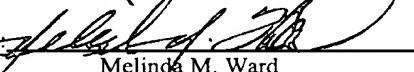
Filed: June 27, 2001

For: APPARATUS AND METHOD FOR ARGON
PLASMA INDUCED ULTRAVIOLET LIGHT
CURING STEP FOR INCREASING SILICON-
CONTAINING PHOTORESIST SELECTIVITY

) Docket No: LAM2P257
)
)
)
)
)
)
)
)

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 on **October 27, 2003**.

Signed: 
Melinda M. Ward

REQUEST FOR RECONSIDERATION

Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

This Communication is in response to the Office Action dated August 29, 2003.
Please amend the specification and consider the following arguments:

Amendments to the Specification begin on page 2 of this paper.

A current listing of the claims are provided for the Examiner's convenience which begins on page 3 of this paper.

Remarks/Arguments begin on page 6 of this paper.

RECEIVED
NOV 04 2003
GROUP 1700